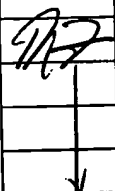
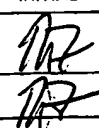



FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)	ATTY. DOCKET NO. ASMJP.128AUS	APPLICATION NO. Unknown 10/618,900
	APPLICANT Akira Shimizu, et al.	
	FILING DATE Herewith	GROUP Unknown 1763

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)

FOREIGN PATENT DOCUMENTS								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	1.	6-316765	11/15/94	Japan (Pat. No. 3112721 issued 9/22/00)			abstract	
	2.	2000-199067	07/18/00	Japan			abstract	
	3.	2001-11634	01/16/01	Japan			abstract	
	4.	2001-148347	05/29/01	Japan			abstract	

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
	5.	John J. Sullivan, et al. Optimization of the Copper Precursor Delivery for CVD Deposition Process, Technical Report, MKS Instruments, Inc. Andover, MA 01810, pages 1-6
	6.	Direct Liquid Injection System, Japan MSK, Nikko No. 97, 10.08.200.

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063003

EXAMINER		DATE CONSIDERED	May 2, 2005
*EXAMINER: INITIAL IF CITATION CONSIDERED. WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP § 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.			